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It has been presented that an SOS-MOS transistor can be a dynamic RAM cell by itself without any additional storage capacitor.<sup>1)</sup> The new memory cell is called the "Charge Pumping memory" (CP-memory) cell. In this paper, the CP-memory is described as a memory array and the selective READ/WRITE operations are validated. The CP-memory is suitable for a large scale high density RAM because it has such advantages as non-destructive readout and non capacitance-ratio problem as well as the simple cell structure.

The information of the CP-memory cell is stored in the floating substrate of an SOS-MOS transistor as a potential difference. READ is carried out by measuring the threshold voltage change (the substrate bias effect). WRITE 'l' is performed by charge pumping; the channel carriers are injected into the substrate and recombine there, resulting in the reverse-biased junctions at the source and drain. WRITE '0' is performed by the avalanche multiplication at a junction; the majority carriers are injected into the substrate.

The CP-memory test structures were made in a conventional p-channel selfaligned silicon gate process, using the (100) 1.0  $\mu$ m thick non-doped silicon epitaxial film on sapphire. The film was doped n-type by phosphorus ion implantation at 180 keV to  $4 \times 10^{12}$  cm<sup>-2</sup> through the gate oxide. The gate oxide thickness was 700 Å. The threshold voltage was 4 V.

A memory array of the CP-memory is shown in Fig.l. The selective operations were proved using a test CP-memory; both the channel length and width are 40  $\mu$ m. The voltages for the operations are summarized in Table I. For storage, the bit lines are kept at the power supply voltage  $V_{CC}$  and the word lines at zero volt. Information in a particular memory cell MC<sub>1</sub> is read when the selected bit line B<sub>1</sub> is set at zero volt and the word line  $W_1$  is set at a readout voltage  $V_R$ , where  $V_R$  is larger than the threshold voltage and low enough to avoid charge pumping. The output voltage  $V_{OUT}$  corresponding to the drain current of the CP-memory cell was obtained as 6 mV or 18 mV, depending upon whether '1' or '0' is written. To write '1' in the cell MC<sub>1</sub>, the bit line B<sub>1</sub> is set at zero volt and a charge pumping pulse  $V_{CP}$  is applied to the word line  $W_1$ . Charge pumping at the cell MC<sub>3</sub> is excluded by keeping B<sub>2</sub> at  $V_{CC}$ . Figure 2(a) shows that '1' is written in MC<sub>1</sub> by the pulse  $V_{CP}$  and the '1' is measured by the pulse  $V_R$ . Whereas the '0' in MC<sub>3</sub> is not affected by the pulse  $V_{CP}$ , since B<sub>2</sub> is kept at  $V_{CC}$ , as shown in Fig.2(b).

-69-

To write '0' in  $MC_1$ , every word line except  $W_1$  is set at  $V_{CC}$  and an avalanche multiplication pulse  $V_{AVA}$  is applied to  $B_1$ . The pulse height  $V_{AVA}$  is adjusted to a proper value to exclude the multiplication at the cell  $\mathrm{MC}_2$  whose gate voltage is aet at  $V_{CC}$ . Figure 3(a) shows that '1' written in MC<sub>1</sub> is changed to '0' by the pulse  $\rm V_{AVA}$  . Whereas the 'l' in MC\_2 is not altered by  $\rm V_{AVA}$  because W\_2 is set at  $V_{\rm CC}$ , as shown in Fig.3(b). It should be noted that the non-destructive readouts of '1' and '0' are shown in Figs. 2(a) and 3(a), respectively.

The similar results were also obtained for the CP-memory test array shown in Fig.4; the channel length was 8 Jm and width 10 Jm. Reference

1) N.Sasaki et al. : 1978 IEDM Tech. Dig. (1978) 356.



Fig.3 Effect of the avalanche multiplication pulse.

-70 -